# Polarized Photocathode Research Collaboration PPRC

R. Prepost - University of Wisconsin Cornell ALCW July 13-16 2003

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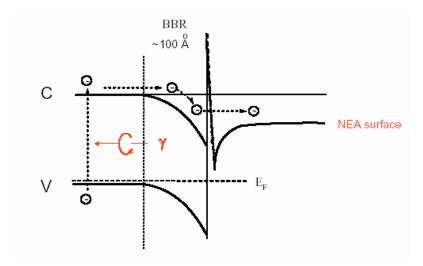
#### Some Considerations

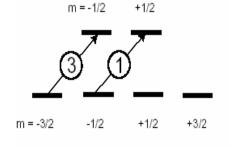
- Technique is Bandgap Engineering of Strained GaAs.
- Polarization will be < 100% But 90% possible.
- Active layer must be < 10% of photon absorption length to preserve strain and polarization.
- Uniform Strain over larger thickness in principle possible with Superlattice structures
- Strained GaAs used at SLAC since 1986 with ~85% Polarization and ~.2% QE.
- R & D has been continuous since 1985.

#### Outline

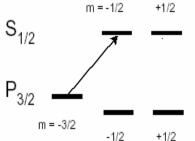
- Polarized photoemission
- Standard SLC photocathode
- Surface charge limit
- Charge limit vs. doping
- Polarization vs. doping
- High gradient doped strained GaAsP
- High gradient doped strained superlattice
- · Atomic-hydrogen cleaning
- Summary

#### Polarized photoemission





Unstrained GaAs



Strained GaAs

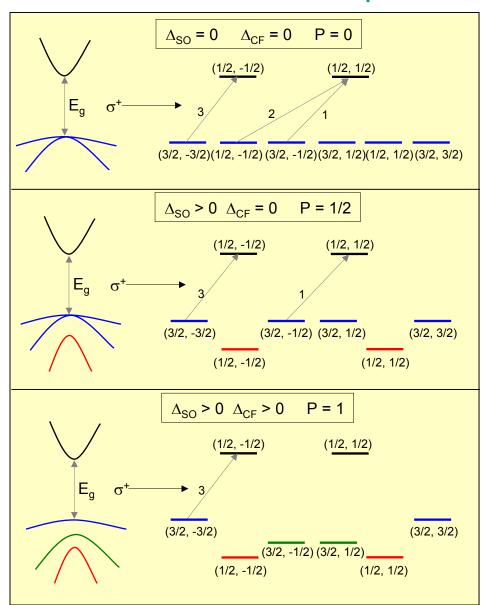
- Circularly polarized light excites electron from valence band to conduction band
- Electrons drift to surface
  L < 100 nm to avoid depolarization</li>
- Electron emission to vacuum from Negative-Electron-Affinity (NEA) surface

NEA Surface Cathode "Activation"

- Ultra-High-Vacuum < 10<sup>-11</sup> Torr
- · Heat treatment at 600° C
- Application of Cesium and NF<sub>3</sub>



# Schematic diagram of near-gap optical transition for circularly polarized light



$$P = \frac{\left| I \downarrow - I \uparrow \right|}{\left| I \downarrow + I \uparrow \right|}$$

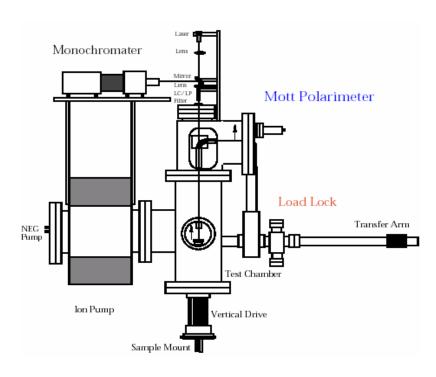
$$I = \left| \left\langle \Psi_f \middle| H_{\text{int}} \middle| \Psi_i \right\rangle \right|^2$$

$$H_{\rm int} = X + iY$$
 for  $\sigma^+$  light

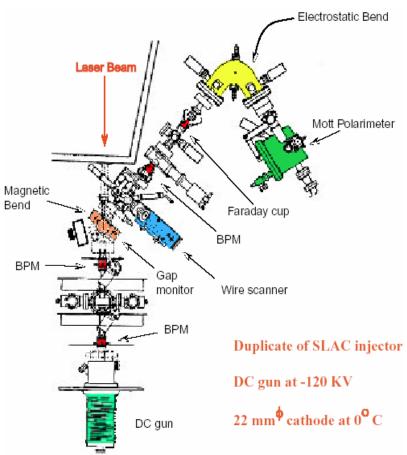
Ideal material for SPES application

- Direct band gap
- · Large spin-orbit splitting
- Large and positive crystal field splitting

#### **Facilities**



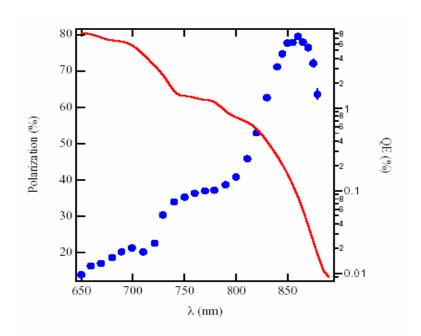
QE and Polarization at 20 kV

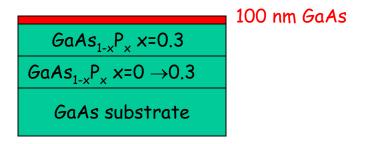


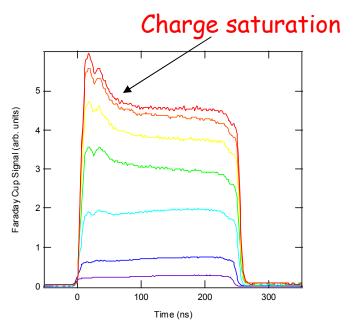
 QE and Polarization at 120 kV under accelerator condition

#### Standard SLC Strained GaAs

- 100 nm GaAs grown on GaAsP
- Uniformly doped at 5×10<sup>18</sup> cm<sup>-3</sup>
- Peak polarization ~80%
- QE ~0.2 0.3%
- Max. charge ~7 ×10<sup>11</sup> e-/270ns

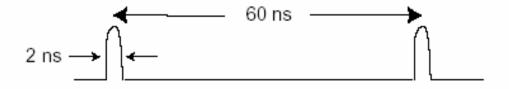






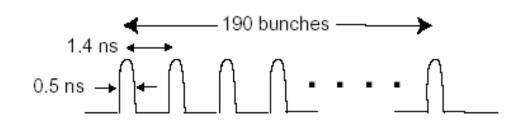
#### Beam structure

SLC beam



1.6 x 10<sup>11</sup> e-/bunch achieved

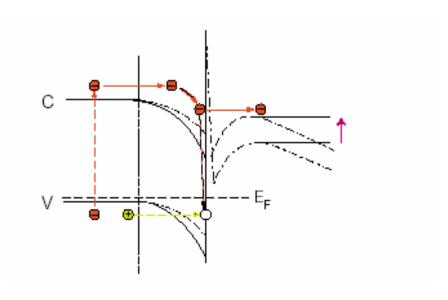
NLC beam



 $1.4 \times 10^{10}$  e-/bunch x 190 bunches =  $2.7 \times 10^{12}$ /train

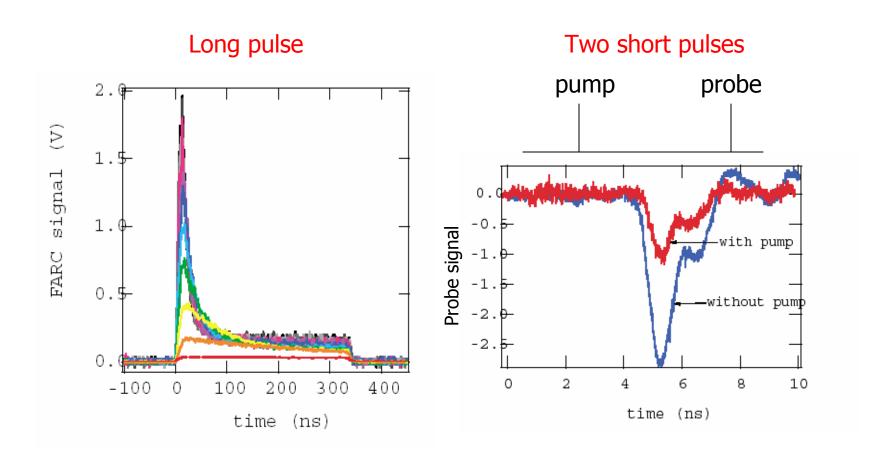
## Surface Charge Limit

- Photon absorption excites electrons to conduction band
- Electrons can be trapped near the surface; electron escape prob. < 20%</li>
- Electrostatic potential from trapped electrons raises affinity
- Affinity recovers after electron recombination
- Increasing photon flux counterproductive at extremes



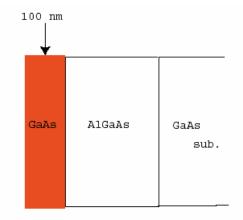
TESLA does not have a charge limit problem.

## Charge limit (cont.)



## Higher doping solves charge limit problem.

Phys. Lett. A282, 309 (2001)



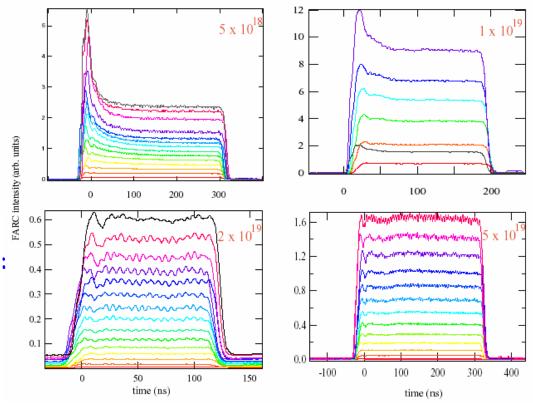
Four samples with different doping level:

5×10<sup>18</sup> cm<sup>-3</sup>

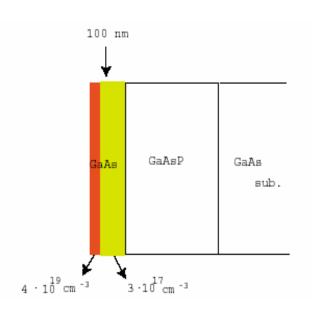
 $1 \times 10^{19} \text{ cm}^{-3}$ 

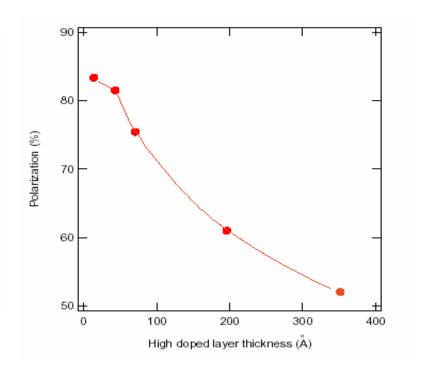
 $2 \times 10^{19} \text{ cm}^{-3}$ 

5×10<sup>19</sup> cm<sup>-3</sup>



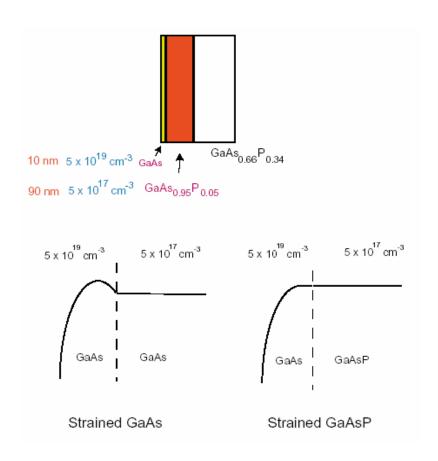
## But higher doping depolarizes spin.

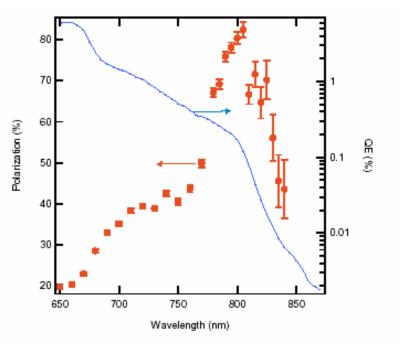




## High-gradient doped strained GaAsP

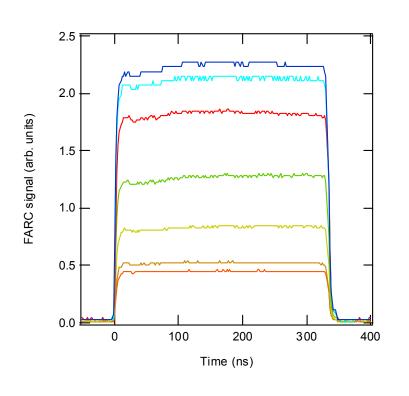
NIM A492, 199 (2002)

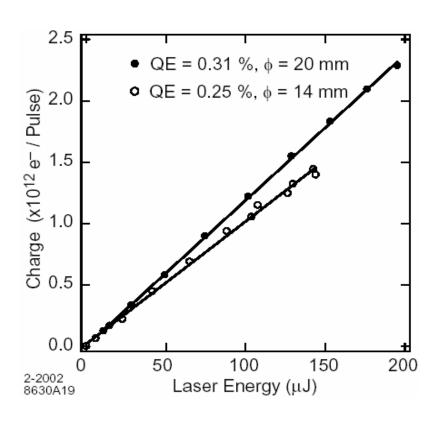




# 80% Polarization and No charge limit

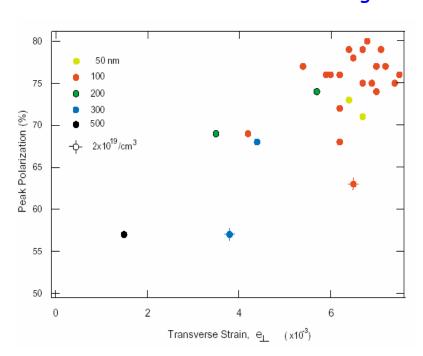
#### E158 cathode



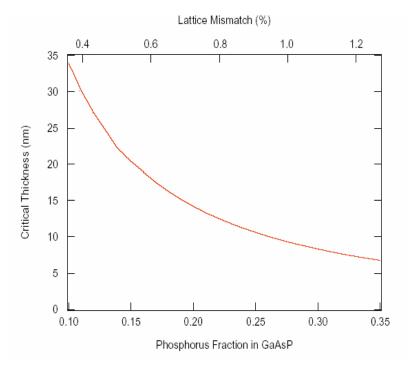


## But polarization is still 80%.

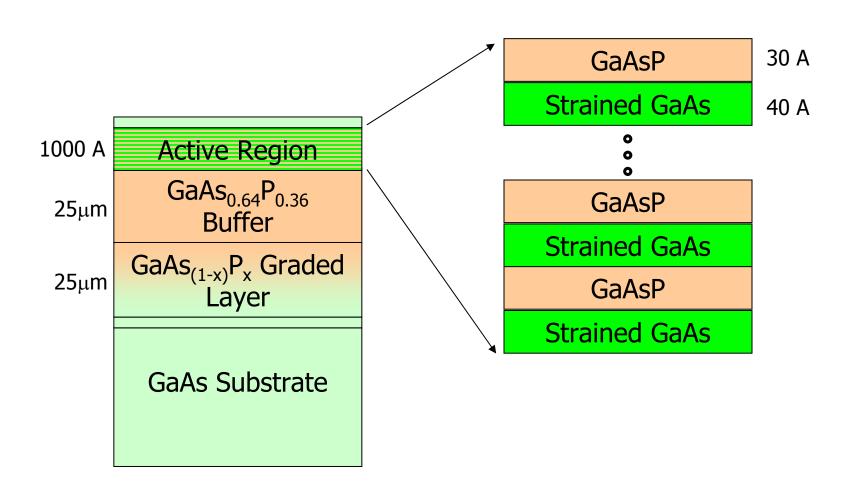
#### Actual strain is 80% of design



#### Strain relaxation



## Strained-superlattice



#### SBIR with SVT Associates

"Advanced Strained-Superlattice Photocathodes for Polarized Electron Souces"

- July 2001 SBIR Phase I awarded
  Very first sample produced 85% polarization
- · Sep. 2002 SBIR Phase II awarded

SLC photocathode

MBE growth

· Be doped

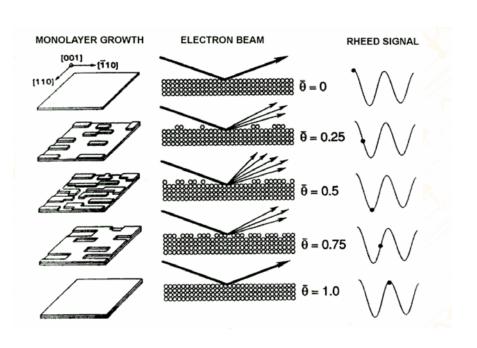
MOCVD growth

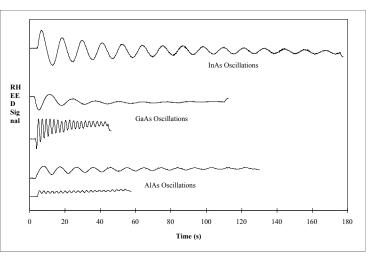
Zn doped

#### **MBE- In Situ Growth Rate Feedback**

Monitoring RHEED image intensity versus time provides layer-by-layer growth rate feedback

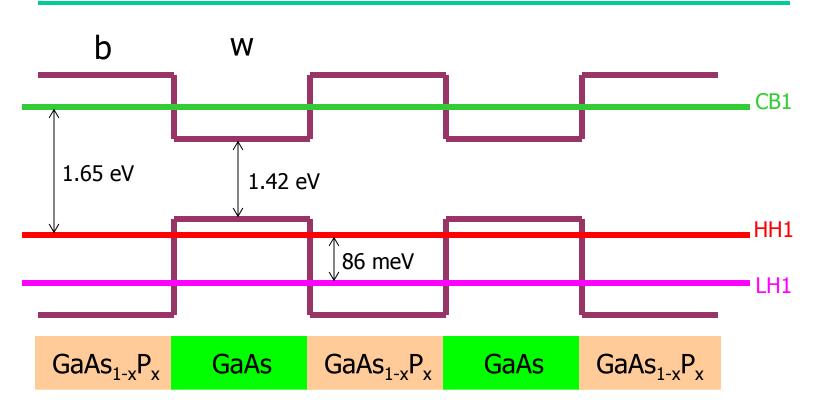
#### Growth at monolayer precision







#### Strained-superlattice band structure



#### Parameters:

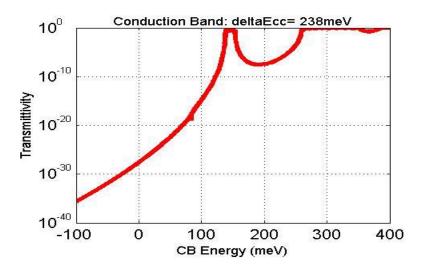
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barrier layer thickness, 30 Å < b < 100 Å well layer thickness , 30 Å < w < 100 Å phosphorus fraction , 0.3 < x < 0.4 No. of periods , active layer \sim 1000 Å
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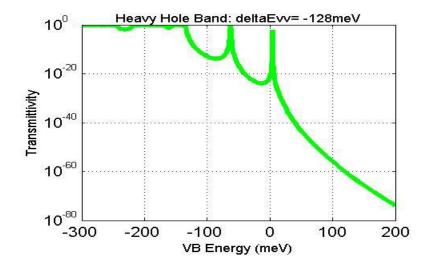
#### Multiple Quantum Well Simulation

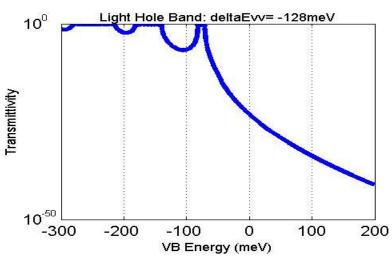
Number of Wells = 10 x in GaAs(1-x)P(x) Barrier = 0.30 Well Width = 50 A Barrier Width = 50 A

Width is measured wrt 1/10000 the peak

Miniband width in CB1 = 25 meV Miniband width in HH1 = 0 meV Miniband width in LH1 = 18 meV

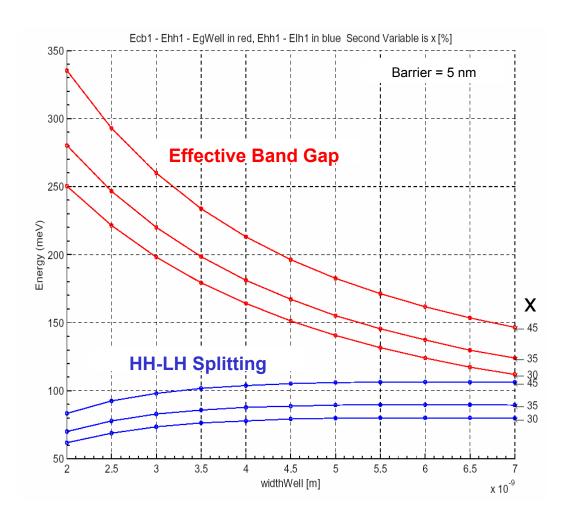






#### Multiple Quantum Well Simulation

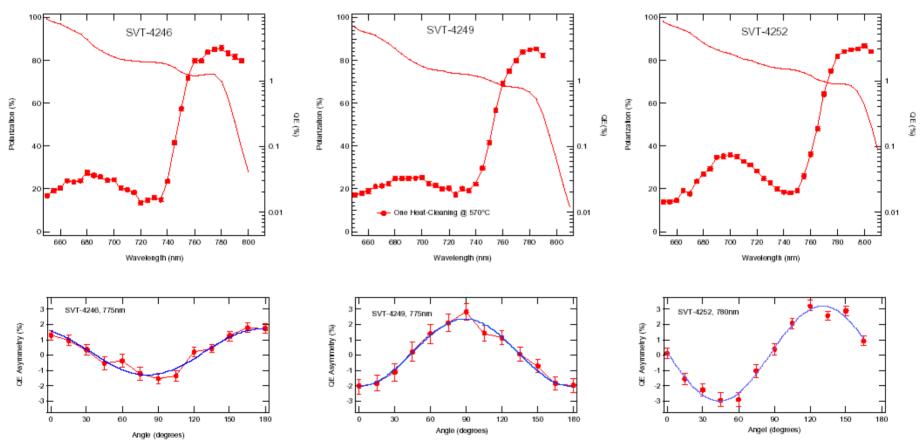
- QE ~ Band Gap
- Polarization ~ HH-LH Splitting



## High gradient-doped superlattice GaAs/GaAsP

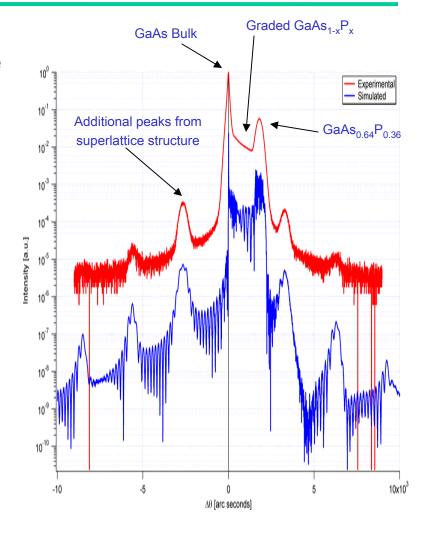
#### Cathode Test Lab

Measurements on SVT-4246, SVT-4249 and SVT-4252.



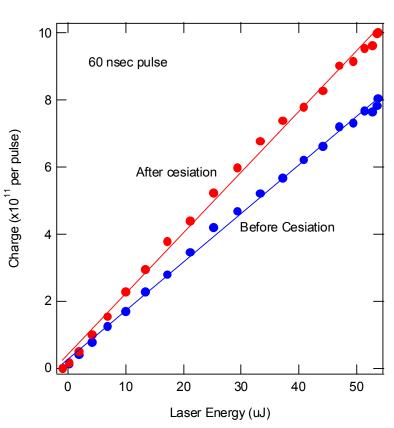
#### Rocking Curve (004) scan from SVT-3682

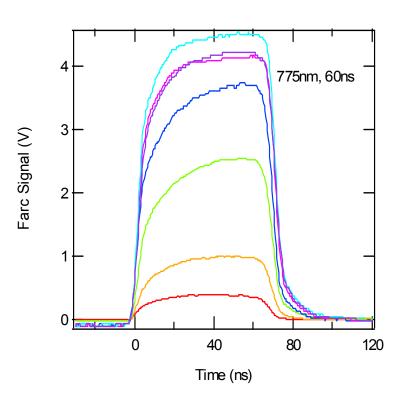
- Both SVT-3682 and SVT-3984 are superlattice cathodes:
  - MBE grown Be-doped (SVT Associates).
  - Barrier width: 30Å
  - Well width: 30Å
  - Phosphorus fraction in GaAsP: 0.36
  - Layer number: 16
  - Highly-doped surface layer
    - thickness: 50Å
- XRD analysis on SVT-3682
  - Well Width = Barrier Width = 32Å
  - Phosphorus fraction in GaAsP: 0.36



## No Charge Limit

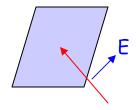




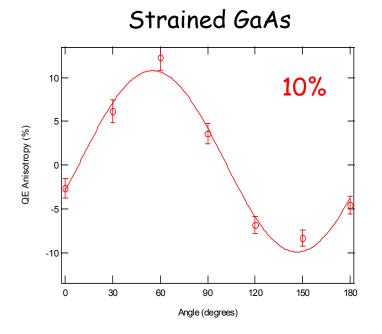


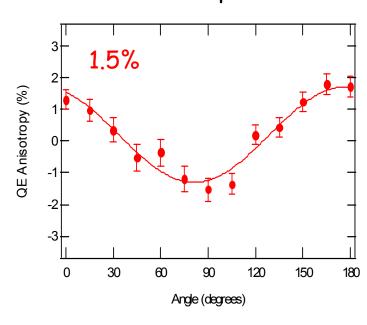
# QE Anisotropy

#### Strain relaxation



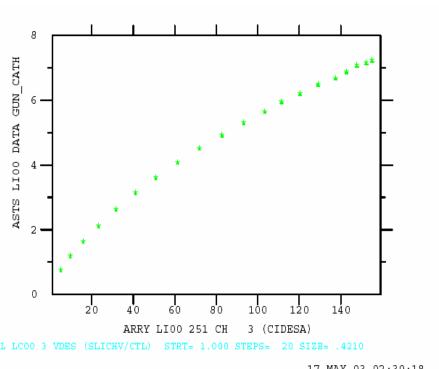
## Strained superlattice





## E158 again

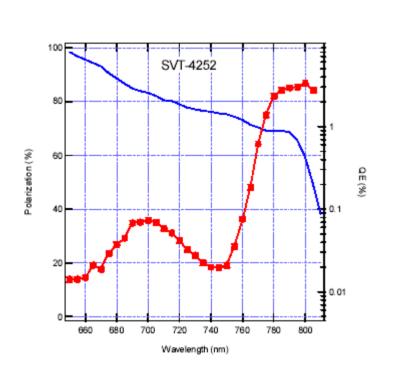
- Cathode installed in May.
- But it shows a charge limit  $\sim 7 \times 10^{11} \text{ e} - /300 \text{ ns}$
- Cannot make NLC train charge but OK for E158.
- What happened?
- The 600° C heat-cleaning is destroying the high gradient doping profile.

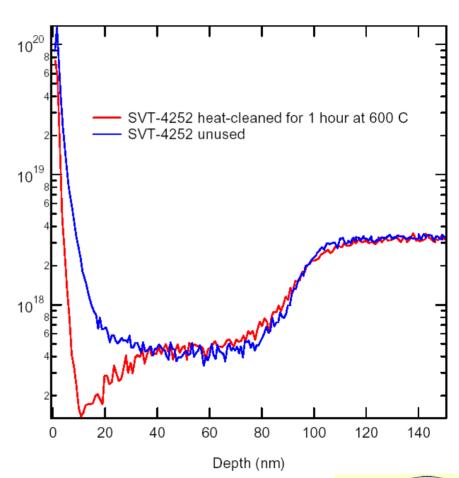


17-MAY-03 02:30:18

## SVT-4252 Shows Charge Limit at Gun Test Lab SVT-4246, SVT-4249 are ok

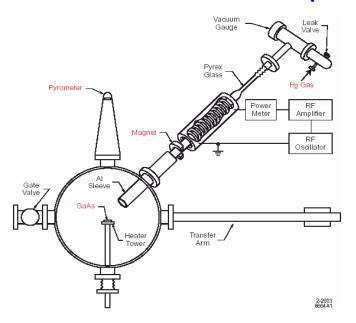
Be concentration (/cm3)







#### Atomic-Hydrogen Cleaning



Bulk GaAs Quantum Efficiency at 670 nm (%) Atomic Hydrogen Cleaning Time (min.)

 $Ga_2O_3 + 4H \rightarrow Ga_2O + 2H_2O\uparrow$ 

 $Ga_2O_3$  comes off at ~600° C. 600° C heat-cleaning: QE ~ 11%  $Ga_2O$  comes off at ~450° C. AHC + 450 ° C heat-cleaning: QE ~15%